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<b>Form 1449 (Modified)</b>  <b>Information Disclosure Statement By Applicant</b>  (Use Several Sheets if Necessary)	Atty Docket No. SCH00051	Serial No.: Unassigned
	Applicant: Schmid Filing Date: Herewith	Group Unassigned

**U.S. Patent Documents**

Examiner Initial	No.	Patent No.	Date	Patentee	Class	Sub-class	Filing Date

**Foreign Patent or Published Foreign Patent Application**

Examiner Initial	No.	Document No.	Publication Date	Country or Patent Office	Class	Sub-class	Translation	
							Yes	No
g.B.	A	WO 95/34798	12/21/95	PCT	G01C	19/56	X	
g.B.	B	WO 98/15799	4/16/98	PCT	G01C	19/56	X	
g.B.	C	DE 19530736	8/22/95	DE	G01P	15/125		X

**Other Documents**

Examiner Initial	No.	Author, Title, Date, Place (e.g. Journal) of Publication
g.B.	D	Geiger, W. et al.; <i>New Designs of Micromachined Vibrating Rate Gyroscopes with Decoupled Oscillation Modes</i> ; 1998; Elsevier Science S.A.
g.B.	E	Lutz, M. et al.; <i>A Precision Yaw Rate Sensor in Silicon Micromachining</i> ; 1997; IEEE.
HR	F	Voss, Ralf, et al.; <i>Silicon Angular Rate Sensor for Automotive Applications with Piezoelectric Drive and Piezoresistive Read-Out</i> ; 1997; IEEE.

Examiner	Helen Kuks	Date Considered	1/20/04
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Examiner: Initial citation considered. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.